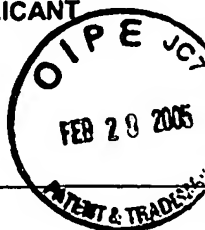


Substitute for form 1449A/PTO

# INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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First Named Inventor Sandhu, Gurtej  
Group Art Unit 2811  
Examiner Name Unknown

Sheet 1 of 1

Attorney Docket No: 303.869US1

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